

In the Abstract

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ABSTRACT OF THE DISCLOSURE

An electrically-coupled micro-electro-mechanical system (MEMS) filter system and method are disclosed. In one embodiment, the MEMS filter system comprises a first microelectromechanical system (MEMS) resonator comprising a first resonating element, a second MEMS resonator comprising a second resonating element, the second resonating element closely spaced and mechanically separate from the first resonating element, wherein the first MEMS resonator is coupled to the second MEMS resonator through the electrostatic force acting between resonating portions of the MEMS resonators, and additional MEMS resonators electrically coupled to the first MEMS resonator, the second MEMS resonator, or the first and second MEMS resonators.